

METHOD AND APPARATUS FOR HIGH-SPEED INSPECTION AND REVIEW

Abstract of the Disclosure

5 One embodiment disclosed relates to an apparatus for substrate  
inspection and review. The apparatus includes at least a first subsystem, a  
processor, and a second subsystem. The first subsystem is used for inspecting said  
substrate. The processor is utilized for identifying regions of said substrate for  
review. The second subsystem is used for reviewing at least a portion of said  
10 identified regions.